The 2nd International Student Workshop on Electrical Engineering

Date: March 11, 2010
Venue: Meijyo University, Japan

Organized and preceded by students

Organizing Chairperson:

S. Iwashita (Kyushu University, Japan)

Supported by

- Good Practice Project for Promotion of Systematic Graduate Education,
- Department of Electrical Engineering,
- Graduate School of Information Science and Electrical Engineering,
  Kyushu University, Japan

Student GP Session (10) (8min+2min Q&A)

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| 15:15 | S-1     | A Stable Large-Volume Fluorine Negative-Ion Source for Ultrafine Etching | M Abid Imtiaz, T. Mieno  
Shizuoka University, Japan |
| 15:25 | S-2     | Effects of amplitude modulation of RF discharge voltage on ion saturation current | Hiroshi Miyata, Shinya Iwashita, Yasuyuki Yamada, Kazunori Koga, Masaharu Shiratani
  Kyusyu University, Japan |
| 15:35 | S-3     | Synthesis dynamics of nanoparticles produced by laser ablation of a solid target immersed in pressurized water | Wafaa Soliman, Noriharu Takada, Koichi Sasaki
  Nagoya University, Japan |
| 15:45 | S-4     | XPS Analysis of Plasma-Polymer Interactions for Organic-Inorganic Hybrid Materials | Ken Cho, Kosuke Takenaka, Yuichi Setsuhara, Masaharu Shiratani, Makoto Sekine, Masaru Hori
  Osaka University, Japan |
15:55  S-5  Ha emission intensity measurements of H₂ + Ar + C₇H₈ plasmas in H-assisted plasma CVD reactor
Takuya Nomura, Yuki Korenaga, Kazunori Koga, Masaharu Shiratani, Yuichi Setsuhara, Makoto Sekine, Masaru Hori
Kyushu University, Japan

16:05  S-6  Ar/H₂O plasma treatment of multiwall carbon nanotubes for dispersion improvement in water
Changlun Chen, Akihisa Ogino, Bo Liang, Masaaki Nagatsu
Shizuoka University, Japan

16:15  S-7  Deposition of n-type a-Si:H using SiH₄+PH₃ multi-hollow discharge plasma CVD
Kenta Nakahara, Hiroshi Sato, Yuuki Kawashima, Kazunori Koga, Masaharu Shiratani
Kyushu University, Japan

16:25  S-8  Surface temperature rise of a-Si:H films during deposition in silane multi-hollow discharges
Yuki Kawashima, Kenta Nakahara, Hiroshi Sato, William Makoto Nakamura, Kazunori Koga, Masaharu Shiratani
Kyushu University, Japan

16:35  S-9  Numerical Analysis on Heat Convection in the Synthesis of Single Walled Carbon Nanotubes by Arc Vaporization
Guodong Tan, Tetsu Mieno
Shizuoka University, Japan

16:45  S-10  Effect of Post-Baking on Copper Adhesion to Polyimide Films Treated by High Density Microwave Plasma
Kenji Usami, Tatsuo Ishijima, Hirotaka Toyoda, Kiyoshi Iseki, Hideo Sugai
Nagoya University, Japan

19:00-20:30 Banquet